

CLAIMS

What is claimed is:

1. A process for measuring stress on a surface having an insulating coating by measuring the resistivity of said coating, comprising using as said coating a silica-stabilized dielectric film.
2. The process as claimed in Claim 1 wherein said silica-stabilized dielectric film is a diamond-like atomic-scale composite material.
3. A surface containing dielectric sensors suitable for measuring stress on the surface, which comprises a surface material and an insulating dielectric coating on said surface material, said insulating coating comprising a silica-stabilized dielectric film.
4. The surface as claimed in Claim 3 wherein said silica-stabilized dielectric film is a diamond-like atomic-scale composite material.